

Drafts

Pending

Active

- L1: (3074) trench near capacitor
- L2: (594) 1 and ((buried or strap) near (strap
- L3: (568) 2 and etch\$3
- L4: (39) 3 and ((gate or sidewall or spacer) n
- L5: (29) 4 and (trench.clm. or capacitor.clm.)
- L6: (21) 5 and contact.clm.

Failed

Saved

Favorites

Tagged (0)

UDC

Queue

Trash

File Edit View Tools Window Help

Doc: USPTO:US 69104

Description: 1. SP

5 and contact.clm.

Abstract Abstract Show Hide

	U	I	FT	P	Document ID	Issue Dat	Pages	Title	Current OR	Current XR	Retrieval	Inventor	S	C	J	A	
1	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030224611	20031204	60	Manufacturing method of	438/706			Seta, Shoji et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
2	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030082876	20030501	28	Vertical DRAM	438/243	257/302		Mandelman, Jack A.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
3	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 2003008469	20030109	28	punchthrough stop self- DRAM cell capacitor and	438/396	257/E21.01	21	Hwang, Yoo-Sang et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
4	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020163842	20021107	7	DRAM cell configuration and method for fabricat	365/200			Benzinger, Herbert et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
5	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020102843	20020901	88	Semiconductor device and manufacturing metho	438/672	257/E21.25	21	Seta, Shoji et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
6	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020066925	20020606	18	Structure and method for forming a body cont	257/329	257/E21.65	31	Gruening, Ulrike et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
7	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020059899	20020523	60	Manufacturing method of	117/97	117/94		Seta, Shoji et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
8	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6660581	20031209	21	Semiconductor devices b Method of forming	438/242	257/E21.25	438/243	Yang, Haining et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
9	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6642566	20031104	15	single bitline contact Asymmetric inside	257/302	438/270	257/301	Mandelman, Jack A.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
10	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6605542	20030812	56	Spacer for vertical tra Manufacturing method of	438/700	257/E21.25		Seta, Shoji et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
11	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6593612	20030715	17	Semiconductor devices b Structure and method	257/301	257/302	21	Gruening, Ulrike et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
12	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6479343	20021112	27	for forming a body cont DRAM cell capacitor and	438/253	257/E21.65	257/E21.01	Hwang, Yoo-Sang et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

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Default operator:

☒ **Europe**
☐ **Highlight all hit terms initially**

9 and ((spacer\$1 or sidewall\$1 or (side adj wall)) near (mask or .
 etch\$3))

U	1	PT	P	Document ID	Issue	Date	Pages	Title	Current OR	Current XRef	Inventor	S	C
1	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	US 20030169629 A1	20030911	49		Semiconductor memory cell configuration and a method for producing the configuration	365/200	257/E21.652	Goebel, Bernd et al.	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>
2	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	US 20020185469 A1	20021212	44		Method of micromachining a multi-part cavity	216/41	257/E21.218; 257/E21.235	Podlesnik, Dragan et al.	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>
3	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	US 20020163842 A1	20021107	7		Dram cell configuration and method for fabricating the dram cell configuration	365/200		Benzinger, Herbert et al.	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>
4	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	US 20020066925 A1	20020606	18		Structure and method for forming a body contact for vertical transistor cells	257/329	257/E21.653; 438/212	Gruening, Ulrike et al.	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>
5	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	US 6548850 B1	20030415	18		Trench capacitor configuration and method of producing it	257/301	257/296; 257/E21.653	Gernhard, Stefan et al.	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>
6	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	US 6451648 B1	20020917	11		Process for buried-strap self-aligned to deep storage trench	438/243	257/E21.651; 438/248; 438/386;	Gruening, Ulrike et al.	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>
7	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	US 6426526 B1	20020730	23		Single sided buried strap	257/302	257/301; 257/E21.652	Divakaruni, Ramachandra et al.	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>
8	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	US 6426253 B1	20020730	19		Method of forming a vertically oriented device in an integrated circuit	438/243	257/E21.551; 257/E21.629; 257/E21.653;	Tews, Helmut Horst et al.	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>
9	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	US 6063658	20000516	21		Methods of making a trench	438/248	257/E21.652; 257/E21.653;	Horak, David	<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>